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Front Matter: Volume 11456

, "Front Matter: Volume 11456," Proc. SPIE 11546, Advanced Laser Processing and Manufacturing IV, 1154601 (30 October 2020); doi: 10.1117/12.2586007

SPIE.

Event: SPIE/COS Photonics Asia, 2020, Online Only

PROCEEDINGS OF SPIE

Advanced Laser Processing and Manufacturing IV

Rongshi Xiao
Minghui Hong
Jianhua Yao
Yuji Sano
Editors

12–16 October 2020
Online Only, China

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SPIE

Volume 11546

Proceedings of SPIE 0277-786X, V. 11546

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Advanced Laser Processing and Manufacturing IV, edited by Rongshi Xiao, Minghui Hong,
Jianhua Yao, Yuji Sano, Proc. of SPIE Vol. 11546, 1154601 · © 2020 SPIE
CCC code: 0277-786X/20/\$21 · doi: 10.1117/12.2586007

Proc. of SPIE Vol. 11546 1154601-1

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Please use the following format to cite material from these proceedings:

Author(s), "Title of Paper," in *Advanced Laser Processing and Manufacturing IV*, edited by Rongshi Xiao, Minghui Hong, Jianhua Yao, Yuji Sano, Proceedings of SPIE Vol. 11546 (SPIE, Bellingham, WA, 2020) Seven-digit Article CID Number.

ISSN: 0277-786X
ISSN: 1996-756X (electronic)

ISBN: 9781510639072
ISBN: 9781510639089 (electronic)

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time)- Fax +1 360 647 1445

SPIE.org

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